EE 466/586 VLSI Design

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Lecture 3 The MOS Transistor (Cont'd)

Alpha Power law Model

Empirically fit real data

Current in saturation

$$I_{DS} = K_S \frac{W}{L} (V_{GS} - V_T)^{\alpha}$$

Current in linear region

$$I_{DS} = K_L \frac{W}{L} (V_{GS} - V_T) V_{DS}$$
$$V_{DSat} = \frac{K_S}{K_L} (V_{GS} - V_T)^{\alpha - 1}$$

Capacitance



Dynamic Behavior of MOS Transistor



The Gate Capacitance





Gate Capacitance



Operation Region	Cgb	C _{gs}	C_{gd}		
Cutoff	C _{ox} WL _{eff}	0	0		
Triode	0	$C_{ox}WL_{eff}/2$	$C_{ox}WL_{eff}/2$		
Saturation	0	$(2/3)C_{ox}WL_{eff}$	0		

Most important regions in digital design: saturation and cut-off

Thin Oxide Capacitance



P-N Junction Capacitance

- The capacitances Csb and Cdb are n+p source/drain junction capacitances for NMOS devices
- For PMOS devices, the capacitances are due to p+n source/drain junctions.

$$I_D = I_S \left(e^{V_J / V_{th}} - 1 \right)$$
$$\phi_B = \frac{kT}{q} \ln \frac{N_A N_D}{n_i^2}$$

P-N Junction Capacitance



Junction Capacitance



$$C_j = \frac{C_{j0}}{(1 - V_D I \phi_0)^m} \qquad \begin{array}{l} m = 0.5: \text{ abrupt junction} \\ m = 0.33: \text{ linear junction} \end{array}$$



Diffusion Capacitance



Diffusion Capacitance (Cont'd)

$$\begin{split} C_{J} = & \frac{C_{jb}A_{b}}{\left(1 - \frac{V_{J}}{\phi_{Bb}}\right)^{mj}} + \frac{C_{jsw}A_{sw}}{\left(1 - \frac{V_{J}}{\phi_{SW}}\right)^{mjsw}} \qquad \qquad A_{sw} = W x_{j} \\ A_{b} = W Y \end{split}$$

$$C_{J} = \frac{C_{jb}A_{b} + C_{jb}A_{sw}}{\left(1 - \frac{V_{J}}{\phi_{B}}\right)^{mj}} = \frac{C_{jb}(A_{b} + A_{sw})}{\left(1 - \frac{V_{J}}{\phi_{B}}\right)^{mj}}$$

Linearizing the Junction Capacitance

$$C_{eq} = \frac{Q_{j}(V_{2}) - Q_{j}(V_{1})}{V_{2} - V_{1}} = \frac{\Delta Q}{\Delta V}$$

$$\Delta Q = \int_{V_1}^{V_2} C(V) dV = \int_{V_1}^{V_2} C_{jb} \left(1 - \frac{V}{\phi_B} \right)^{-m} dV$$

$$C_{eq} = -\frac{C_{jb}\phi_{B}}{(V_{2} - V_{1})(1 - m)} \left[\left(1 - \frac{V_{2}}{\phi_{B}}\right)^{1 - m} - \left(1 - \frac{V_{1}}{\phi_{B}}\right)^{1 - m} \right]$$

Final Expression

$$C_{J} = K_{eq}(C_{jb}WY + C_{jb}x_{j}W) = K_{eq}(C_{jb}Y + C_{jb}x_{j})W = K_{eq}C_{jb}(Y + x_{j})W$$

$$C_J = K_{eq}C_{jb}(Y + x_j)W = C_jW$$

Capacitances in 0.25 µm CMOS process

	C_{ox} (fF/ μ m ²)	C _O (fF/μm)	C_j (fF/ μ m ²)	m_{j}	$egin{array}{c} \phi_b \ (V) \end{array}$	C _{jsw} (fF/µm)	m _{jsw}	$egin{array}{c} \phi_{bsw} \ (V) \end{array}$
NMOS	6	0.31	2	0.5	0.9	0.28	0.44	0.9
PMOS	6	0.27	1.9	0.48	0.9	0.22	0.32	0.9

Overlap Capacitance



Lateral diffusion and fringing

 Diffusion of the heavily-doped source and drain regions under the gate.

fringing
capacitance,
between the sidewall
of the Polysilicon and
the surface of the
drain and source

The Sub-Micron MOS Transistor

Threshold Variations
Subthreshold Conduction
Parasitic Resistances

Threshold Variations



the length (for low V_{DS})

Drain-induced barrier lowering (for low *L*)

Part of the region below the gate is already depleted

- Diffusion of minority carriers
- MOS transistor behaves more like a (lateral) bipolar transistor.
- The substrate is the base region, while the source and drain act as the emitter and collector, respectively.

$$I_{sub} = I_{s} e^{\frac{q(V_{GS} - V_{T} - V_{offinit})}{nkT}} (1 - e^{\frac{-qV_{DS}}{kT}})$$

$$\frac{10I_{sub}}{I_{sub}} = \frac{I_s e^{\frac{q(V_{GS1} - V_T - V_{offset})}{nkT}} (1 - e^{\frac{-qV_{DS}}{kT}})}{I_s e^{\frac{q(V_{GS2} - V_T - V_{offset})}{nkT}} (1 - e^{\frac{-qV_{DS}}{kT}})}$$

$$\therefore 10 = \frac{e^{\frac{q(V_{GS1} - V_T - V_{offset})}{nkT}}}{e^{\frac{q(V_{GS2} - V_T - V_{offset})}{nkT}}} = e^{\frac{q(V_{GS1} - V_{GS2})}{nkT}}$$

$$S = \Delta V_{GS} = \frac{nkT}{q} \ln(10)$$





Summary of MOSFET Operating Regions

- $\Box \text{ Strong Inversion } V_{GS} > V_T$
 - Linear (Resistive) $V_{DS} < V_{DSAT}$
 - Saturated (Constant Current) $V_{DS} \ge V_{DSAT}$
- □ Weak Inversion (Sub-Threshold) $V_{GS} \leq V_T$
 - Exponential in V_{GS} with linear V_{DS} dependence

Parasitic Resistances

Shallower junctions and smaller contact openings